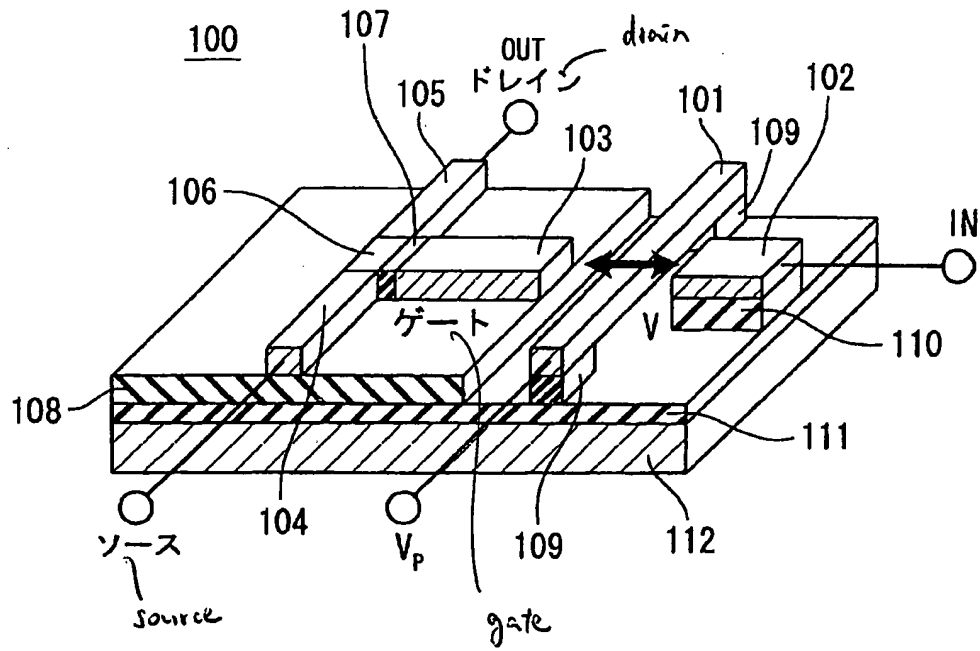
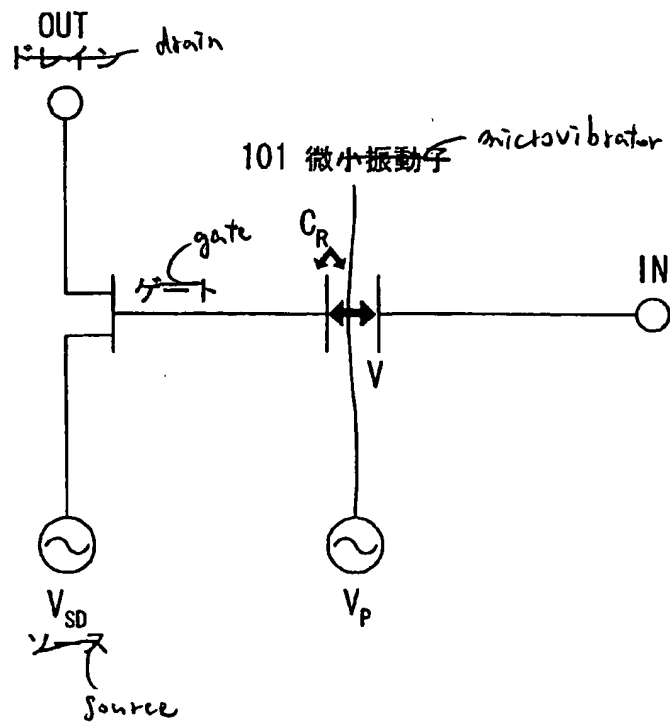


Fig. 1

(a)



(b)



~~[図3]~~ **Fig.3**

(a)

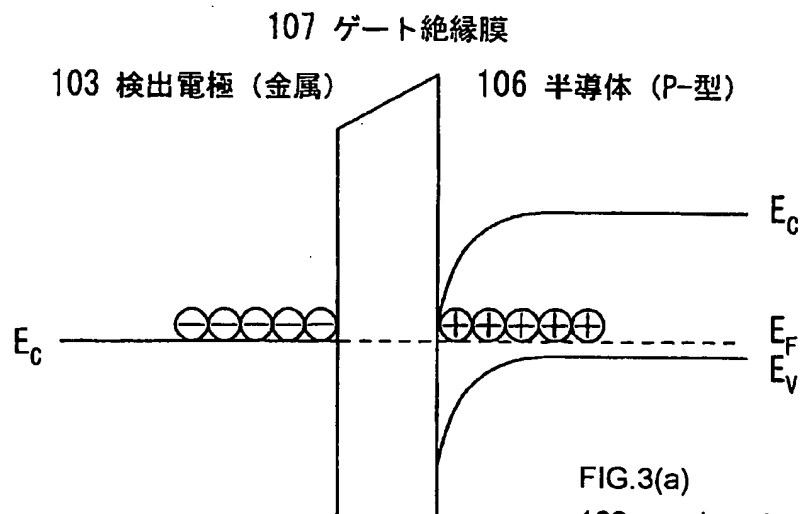


FIG.3(a)

103 sensing electrode (metal)

106 semiconductor (P-type)

107 gate insulating film

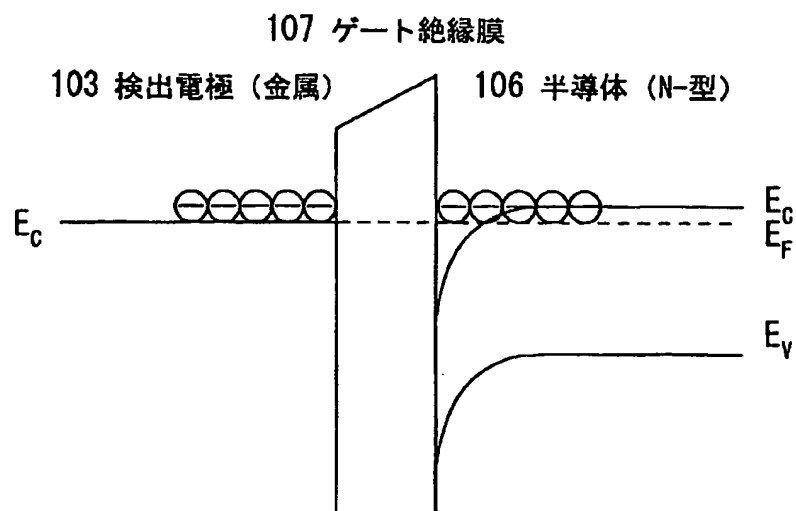
FIG.3(b)

(a)

103 sensing electrode (metal)

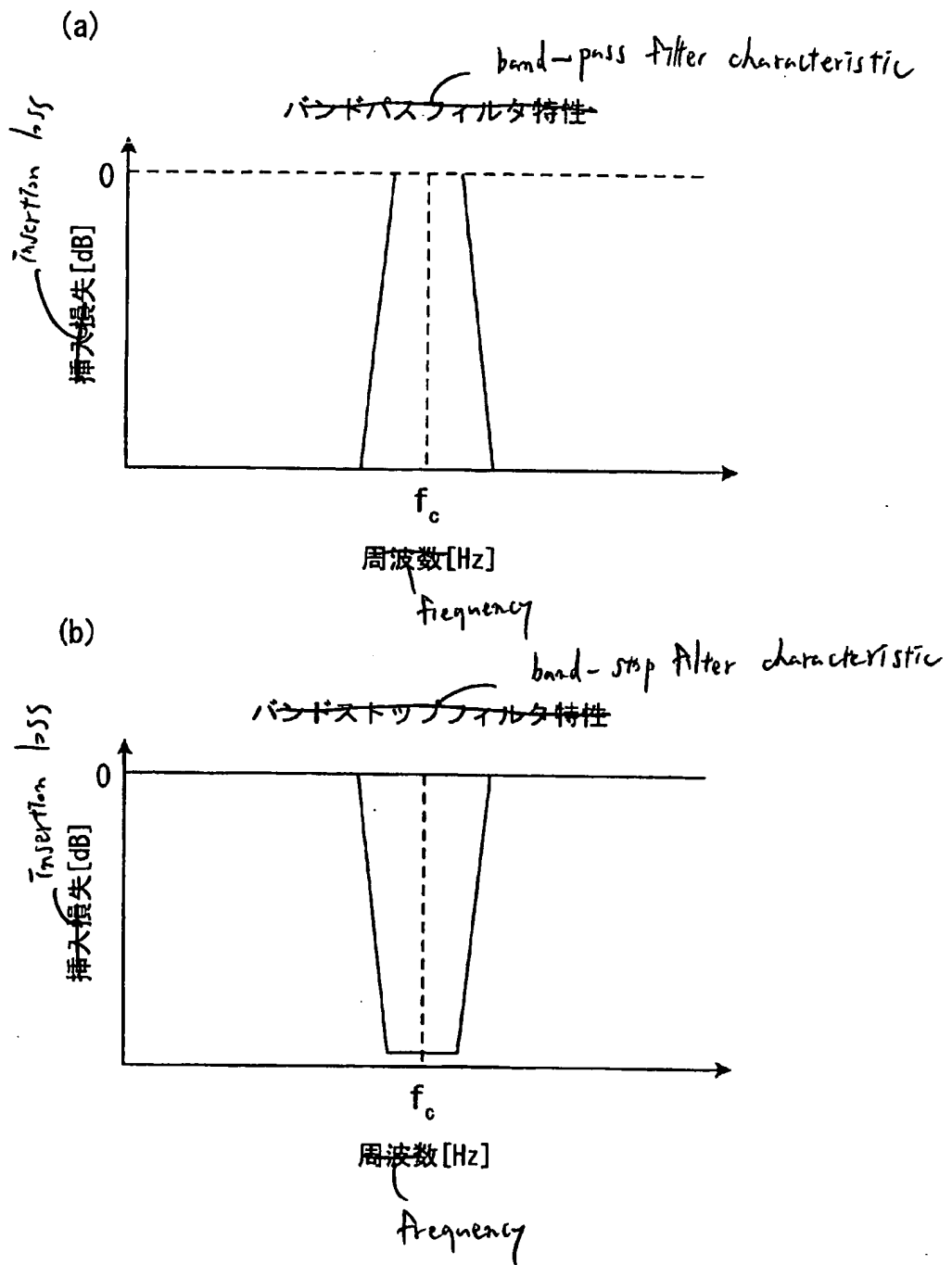
106 semiconductor (N-type)

107 gate insulating film



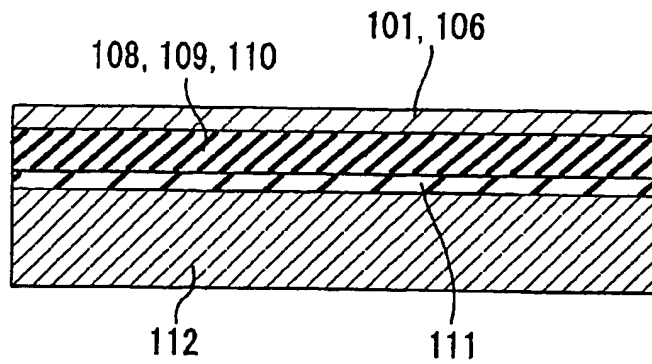
[4]

Fig. 4

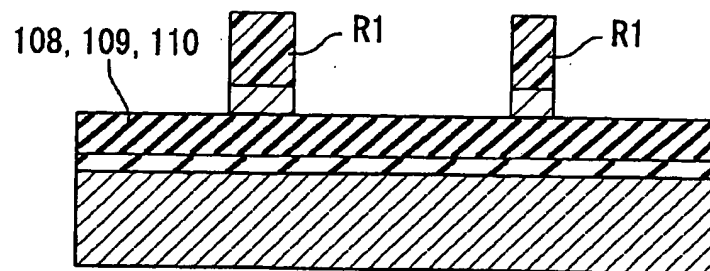


 **Fig. 5**

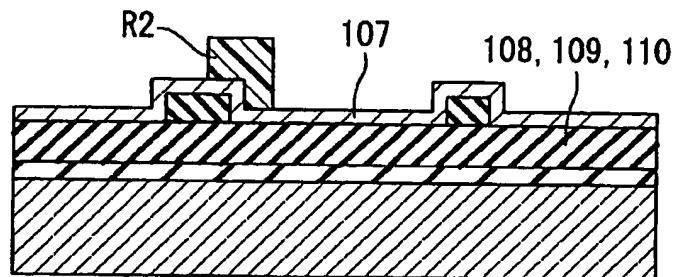
(a)



(b)



(c)



(d)

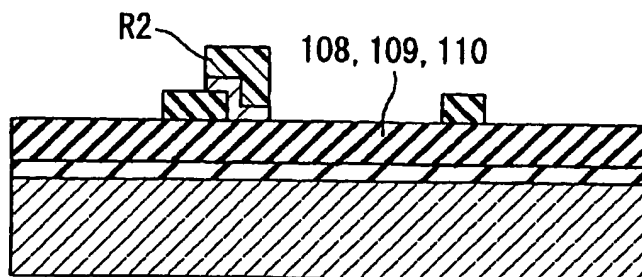


Fig. 6

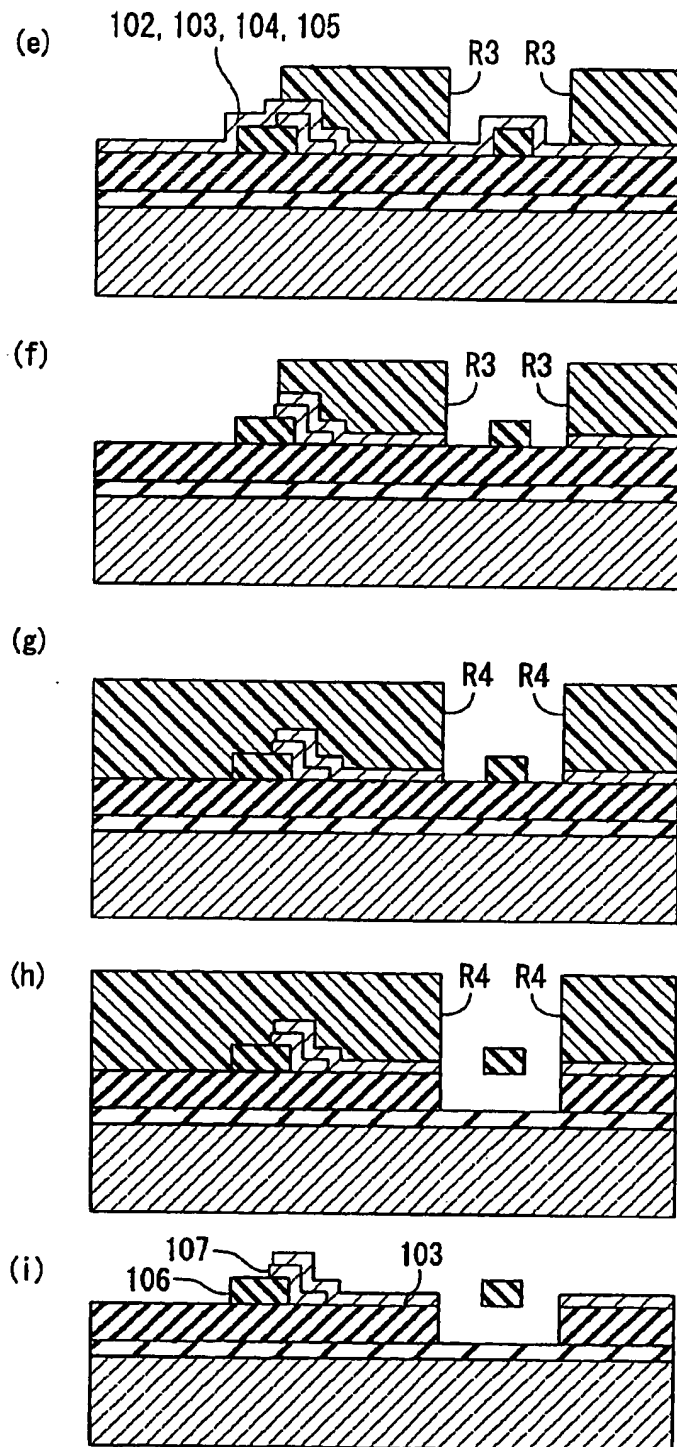
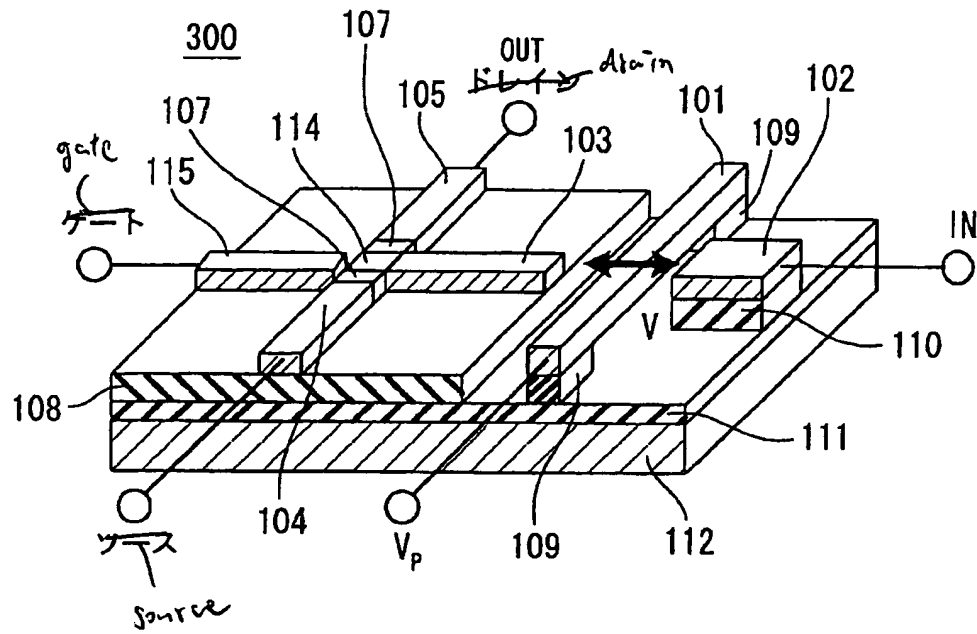


Fig. 7

(a)



(b)

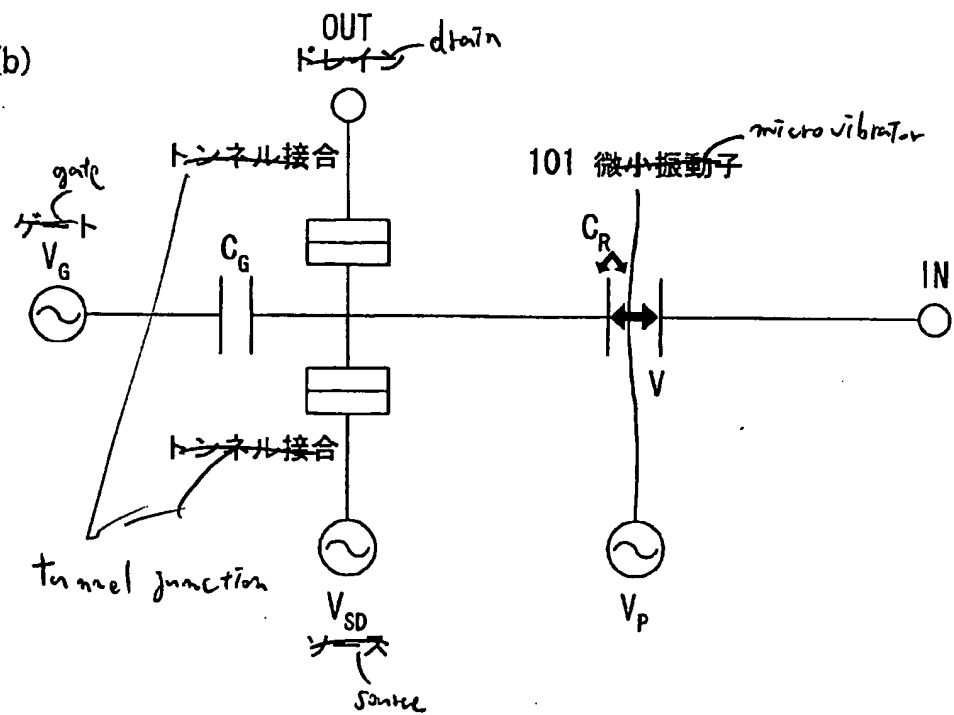
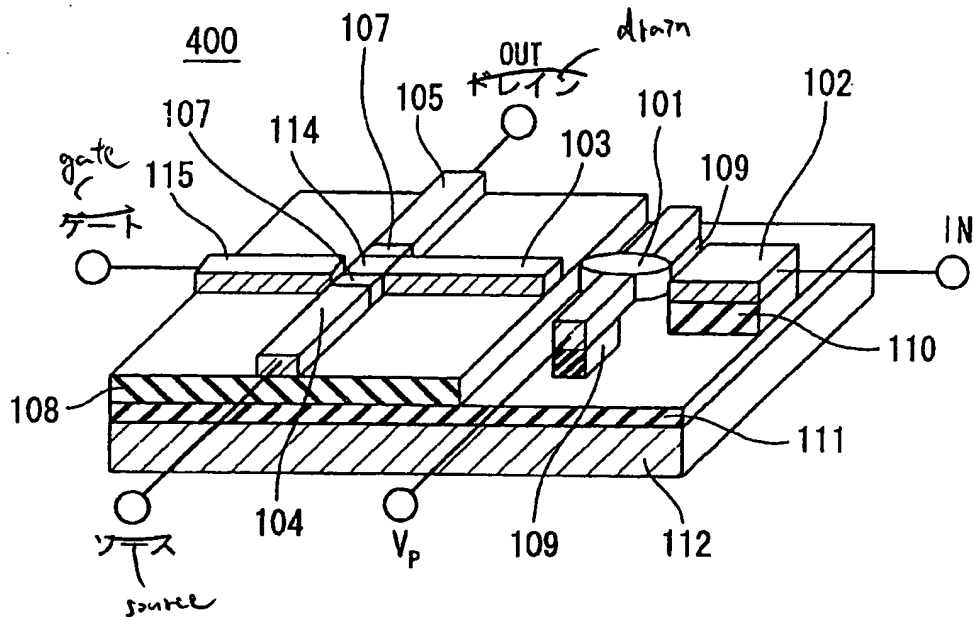
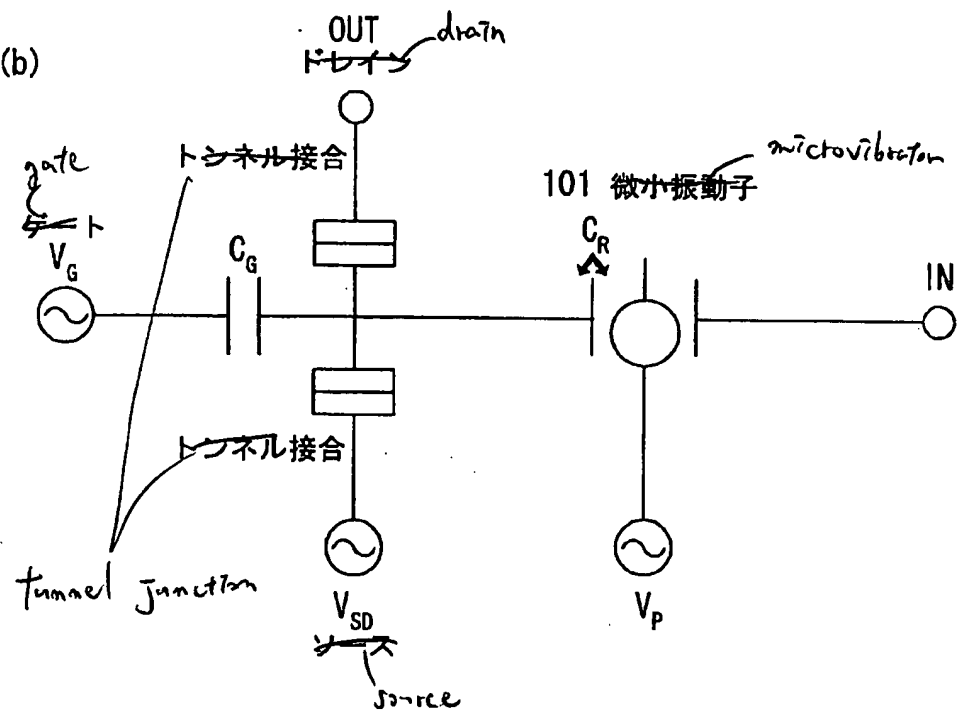


Fig. 8

(a)



(b)



~~図9~~ Fig. 9

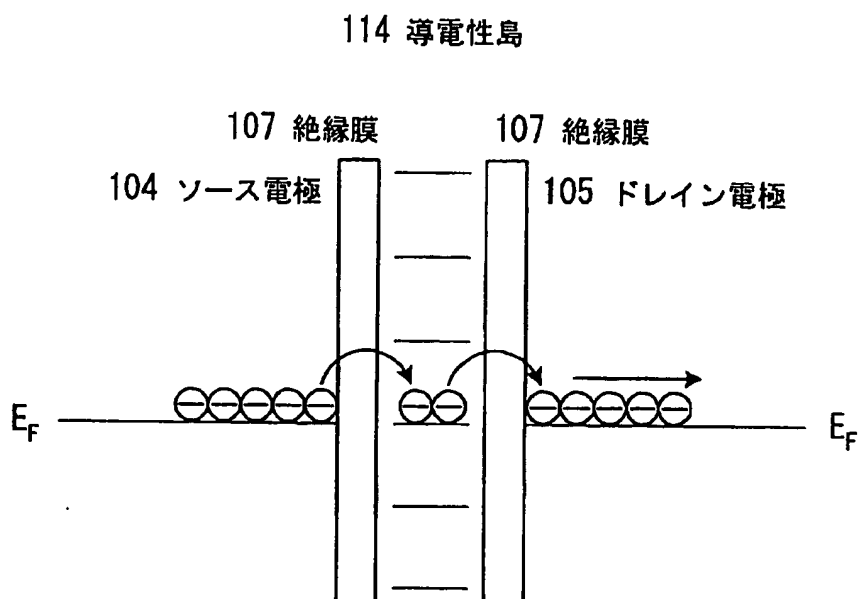


FIG.9:

104 source electrode

105 drain electrode

107 insulating film

114 conductive island

~~図12~~ Fig. 12

